

Session I	ABS	First name	Last name	Poster Title	Topic Name	Affiliation	Country
SA-P01	51	Adéla	Jagerová	Damage accumulation and structural modification in various GaN crystallographic	Ion beam processing of materials	Nuclear Physics Institute, Academy of Sciences of the Czech Republic	Czech Republic
SA-P02	186	Alexander	Suvorov	Experimental studies of channeling implantation of Al ions into 4H-SiC	Ion beam processing of materials	Wolfspeed a CREE Company	USA
SA-P03	129	Alexei	Shestakov	The oscillations of magnetization and derivative of microwave absorption in Hg <sub>0.76</sub> Cd <sub>0.24</sub> Te implanted with Ag <sup>+</sup> ions	Ion beam processing of materials	Kazan E.K. Zavoisky Physical-Technical Institute	Russia
SA-P04	71	Alexey	Shevelev	Joint influence of steered vacuum arc and negative repetitively pulsed bias	Ion beam processing of materials	National Research Tomsk Polytechnic University	Russia
SA-P05	216	André	Ruza	Implantation in copper based high entropy alloys	Ion beam processing of materials	IPFN, Instituto Superior Técnico, Campus Tecnológico e Nuclear, Loures	Portugal
SA-P06	145	Bruno	Teixeira	Tuning the magnetic anisotropy in perpendicular magnetic tunnel junctions by means of ion implantation	Ion beam processing of materials	Physics Department & i3N, University of Aveiro	Portugal
SA-P07	88	Daniela	Pereira	Electrical and Structural Characterization of Molybdenum Oxide Lamellar Crystals	Ion beam processing of materials	IPFN, Instituto Superior Técnico, Campus Tecnológico e Nuclear, Loures	Portugal
SA-P08	74	Danil	Ignatov	Low-Energy Immersion Ion-Plasma Nitriding in the Plasma of Non-Self-Sustained Arc Discharge with Hot Filament and Hollow Cathodes	Ion beam processing of materials	Institute of High Current Electronics, Siberian Branch	Russia
SA-P09	134	Debasree	Chowdhury	Nanostructuring of semiconductor surfaces with sputter-threshold energy Ar <sup>+</sup> ion irradiation	Ion beam processing of materials	Saha Institute of Nuclear Physics	India
SA-P10	33	Der-Sheng	Chao	Effects of He-ion Energy on Blistering Characteristics in H/He and He/H Co-implanted Si	Ion beam processing of materials	Nuclear Science and Technology Development Center, National Tsing Hua University	Taiwan
SA-P11	142	Dilnoza	Tashmukhamedova	Electronic structure of nanoscale structures are created on the basis of silicon	Ion beam processing of materials	Tashkent State Technical University	Uzbekistan
SA-P12	89	Djibril Ndiack	Faye	Structural and optical characterization of praseodymium doped GaN nanowires and thin films	Ion beam processing of materials	IPFN, Instituto Superior Técnico, Campus Tecnológico e Nuclear, Loures	Portugal
SA-P13	97	Elnar	Imametdinov	Modification of surface graphite by nitrogen and argon plasma on air	Ion beam processing of materials	Moscow aviation institute (National Research University)	Russia
SA-P14	127	Haowen	Zhong	The influence of grain size to the surface modification of intense pulsed ion beam treatment	Ion beam processing of materials	School of Physics and Nuclear Energy Engineering, Beihang University	P.R. China
SA-P15	210	Hiroshi	Koshikawa	Preparation of Conductive Layer on Polyimide Ion-Track Membrane by Ar Ion Implantation	Ion beam processing of materials	Takasaki Advanced Radiation Research Institute, National Institute	Japan
SA-P16	212	Jakub	Ossowski	Molecule-Metal Interface Stability Revealed By Static SIMS	Ion beam processing of materials	Jagiellonian University	Poland
SA-P17	135	João	Cruz	Very high fluence nitrogen implantations in metals and the deficiency method	Ion beam processing of materials	Laboratório de Instrumentação, Engenharia Biomédica e Física da Radiação, FCT/UNL	Portugal
SA-P18	207	Katarzyna	Olejniczak	The Uniformity of Electrical Properties of Asymmetric Track-Etched Single Nanopores	Ion beam processing of materials	Flerov Laboratory of Nuclear Reactions, JINR	Russia/Poland
SA-P19	63	Kevin	Homewood	Band edge modified rare earths implanted in silicon for mid-infrared photodetect	Ion beam processing of materials	Queen Mary University of London	United Kingdom
SA-P20	159	Kingo	Azuma	A Plasma Based Ion Implantation in Aluminum Plasma Generated by High-Power Pulse	Ion beam processing of materials	University of Hyogo	Japan
SA-P21	58	Koumei	Baba	Preparation of Fluorine and Iodine Containing Diamond-like Carbon Films by PSII, Based on Trifluoriodomethane	Ion beam processing of materials	Industrial Technology Center of Nagasaki, Nagasaki University	Japan
SA-P22	198	Krishanlal	Bharuth-Ram	Morphological changes in embedded Fe clusters in MgO following swift heavy ion irradiation	Ion beam processing of materials	Durban University of Technology	South Africa
SA-P23	29	L.D.	Yu	Ion Beam Gem-technology	Ion beam processing of materials	Thailand Center of Excellence in Physics	Thailand
SA-P24	101	Magdalena	Krupska	Surface stability of Fe, Pd and (Fe,Pd) films grown on Si substrates	Ion beam processing of materials	Nanostructure Laboratory, Institute of Physics	Poland
SA-P25	64	Manon	Lourenco	Silicon light emitting diodes made by rare earth ion implantation	Ion beam processing of materials	Queen Mary University of London	United Kingdom
SA-P26	217	Maria	Fialho	Implantation temperature study of Al <sub>x</sub> Ga <sub>1-x</sub> N films grown by MOCVD	Ion beam processing of materials	IPFN, Instituto Superior Técnico, Campus Tecnológico e Nuclear, Loures	Portugal
SA-P27	116	Mariapompea	Cutroneo	Direct patterning on Graphene Oxide using ion beam lithography	Ion beam processing of materials	Nuclear Physics Institute, CAS	Czech Republic
SA-P28	96	Mario	Ueda	Results of measurements of morphology, microstructure and nanoindentation in samples subjected to plasma immersion ion implantation inside metal tubes	Ion beam processing of materials	National Institute for Space Research	Brazil
SA-P29	98	Michail	Zhidkov	Pulsed Ion Beam Induced Changes in a Topography of the Surface Layers of Titanium	Ion beam processing of materials	Belgorod State National Research University	Russia
SA-P30	223	Mohamed	El Bouanani	Ion irradiation and thermal processing for controlled crystallization of Ruthenium and Hafnium silicates based thin films and their properties	Ion beam processing of materials	University of North Texas, Department of Materials Science and Engineering	USA
SA-P31	118	Nabiha	Ben Sedrine	ZnO nanoripples produced by medium energy ion beam sputtering: damage and roughness evolution	Ion beam processing of materials	Departamento de Física e I3N, Universidade de Aveiro	Portugal
SA-P32	62	Norberto	Catarino	Helium and deuterium irradiation effects in Tungsten-based alloys with Titanium	Ion beam processing of materials	IPFN, Instituto Superior Técnico, Campus Tecnológico e Nuclear, Loures	Portugal
SA-P33	160	Omar	El Bounagui	Monte Carlo simulations of electronic energy loss of the heavy ions in polymers	Ion beam processing of materials	HEPL-SM, Faculty of Sciences, Mohammed V University in Rabat	Morocco
SA-P34	125	Pavol	Noga	Synthesis of Al <sub>64</sub> Cu <sub>20</sub> Co <sub>16</sub> complex metallic alloy thin films aided by MeV ion beam annealing	Ion beam processing of materials	Advanced Technologies Research Institute, Faculty of Materials	Slovak Republic
SA-P35	111	Petr	Malinsky	Graphene oxide layers modified by helium energetic ions	Ion beam processing of materials	Nuclear Physics Institute of the CAS	Czech Republic
SA-P36	225	R.E.	Rojas-Hernandez	Optical properties of titania and aluminosilicate glass films doped with Er and Yb	Ion beam processing of materials	Centro de Química Estrutural, Instituto Superior Técnico	Portugal
SA-P37	154	Rodrigo	Mateus	Helium load on W-O coatings using multiple implantation stages	Ion beam processing of materials	IPFN, Instituto Superior Técnico, Campus Tecnológico e Nuclear, Loures	Portugal
SA-P38	50	Romana	Mikšová	A structural study and ion irradiation of the silicon crystal layer	Ion beam processing of materials	Nuclear Physics Institute of the CAS	Czech Republic
SA-P39	80	Rui	Martins	Ni-Ti alloy surface modification by plasma immersion ion implantation	Ion beam processing of materials	IPFN, Instituto Superior Técnico, Campus Tecnológico e Nuclear, Loures	Portugal
SA-P40	231	Sagar	Sen	Influence of Swift heavy ions on the Optical and Electronic properties of Cr doped TiO <sub>2</sub> thin film prepared by Pulsed laser deposition technique	Ion beam processing of materials	School of Instrumentation, Devi Ahilya Vishwavidyalaya	India
SA-P41	38	Samira	Ourabah	Effective charge parameter for Li and O ions in Aluminum, silver, gold, polypropylene and Makrofol foils	Ion beam processing of materials	Ecole Préparatoire en Sciences et Techniques d'Alger	Algerie
SA-P42	20	Sergei	Ghyngazov	Ion Processing of Alumina Ceramics by High-Power Pulsed Beams	Ion beam processing of materials	National Research Tomsk Polytechnic University	Russia
SA-P43	130	Setsuo	Nakao	Effects of source gases on microstructure of diamond-like carbon films prepared by plasma based ion implantation and deposition	Ion beam processing of materials	AIST	Japan
SA-P44	25	Shengqiang	Zhou	Turn on/off the high-temperature ferromagnetism in Si <sub>1-x</sub> Mn <sub>x</sub> thin films through Mn-ion implantation	Ion beam processing of materials	Helmholtz-Zentrum-Dresden-Rossendorf, Institute of Ion Beam Physics and Materials	Germany
SA-P45	106	Solmaz	Mustafaeva	X-ray conductivity of AgGaS <sub>2</sub> single crystals	Ion beam processing of materials	Institute of Physics, Azerbaijan National Academy of Sciences	Azerbaijan
SA-P46	141	Stefan	Facsco	Self-Organized Semiconductor Surface Patterning of Pure and Compound Semiconductor	Ion beam processing of materials	Helmholtz-Zentrum Dresden-Rossendorf	Germany
SA-P47	104	Takaomi	Matsutani	Surface Modification of Triacetylcellulose by Nitrogen Ion for Diaphragm of Environmental Cell Transmission Electron Microscope	Ion beam processing of materials	KINDAI University	Japan

<a href="#">SA-P48</a>	47	Tohru	Nakamura	Homogeneity Evaluation in Mg Implanted GaN Layer by On-wafer Measured Diode Forward Diode Current Mapping	Ion beam processing of materials	Research Center for Micro/Nano Technology, Hosei University	Japan
<a href="#">SA-P49</a>	119	Vladimir	Ovchinnikov	Computer 3D analysis of the field ion microscopy images of platinum irradiated with Ar <sup>+</sup> ions (E = 30 keV)	Ion beam processing of materials	Institute of Electrophysics, UB RAS	Russia
<a href="#">SA-P50</a>	187	Valery	Mikoushkin	Modification of the GaAs Native Oxide Surface Layer into the Layer of the Ga <sub>2</sub> O <sub>3</sub>	Ion beam processing of materials	Ioffe Institute	Russia
<a href="#">SA-P51</a>	188	Valery	Mikoushkin	Formation of a p-Layer on the GaAs Surface by an Ar <sup>+</sup> Ion Beam	Ion beam processing of materials	Ioffe Institute	Russia
<a href="#">SA-P52</a>	17	Vladimir	Kozlov	Characterization of surface layers created in silicon diode structures by argon	Ion beam processing of materials	Power Semiconductors Ltd. & FID GmbH	Russia
<a href="#">SA-P53</a>	46	Wolfgang	Ensinger	Ion Beam Sputter Deposition of Nanofilms onto Rings and Tubes for Corrosion Protection	Ion beam processing of materials	Darmstadt University of Technology, Department of Materials Science	Germany
<a href="#">SA-P54</a>	107	Xiaoyun	Le	Lattice damage and strain in RbTiOPO <sub>4</sub> crystals induced by carbon ion implantation	Ion beam processing of materials	Beihang University	China
<a href="#">SA-P55</a>	202	Yoshihiro	Oka	Preparation of Colloidal Ag Nanoparticle Solution by Cavitation Bubble Plasma	Ion beam processing of materials	University of Hyogo	Japan
<a href="#">SA-P56</a>	208	Yoshikazu	Teranishi	Effect of ion implantation on ceramics materials	Ion beam processing of materials	Tokyo Metropolitan Industrial Technology Research Institute	Japan
<a href="#">SA-P57</a>	110	Yu	Xiao	Microstructure evolution on surface morphology of metallic material under intense pulsed ion beam irradiation	Ion beam processing of materials	Beihang University	P.R.China
<a href="#">SA-P58</a>	3	Yuhong	Li	Redox response of Lu <sub>2-x</sub> Ce <sub>x</sub> Ti <sub>2</sub> O <sub>7</sub> pyrochlores under irradiation	Ion beam processing of materials	Lanzhou University	China
<a href="#">SA-P59</a>	70	Yuki	Torita	Rutherford backscattering study on high dose Mg-ion implanted GaN bulk single crystal	Ion beam processing of materials	Hosei University	Japan
<a href="#">SA-P60</a>	136	Yury	Danilov	Ion-Dose Dependence of Laser Annealing Effects for Mn <sup>+</sup> -Implanted GaAs	Ion beam processing of materials	Lobachevsky State University	Russian Federation
<a href="#">SA-P61</a>	126	Yutaka	Inouchi	Brittleness Modification of Synthetic Quartz Glass Surface by Ion Beams	Ion beam processing of materials	Nissin Ion Equipment Co., Ltd	Japan
<a href="#">SA-P62</a>	200	Cédric	Mastail	Influence of Deposition Parameters on the Tilt-angle of TiN nano-columns Grown at Oblique Angle Deposition: kMC simulations vs. experiments	Ion beam processing of materials	Institut Pprime, Département de Physique et Mécanique des Matériaux, Université de Poitiers-CNRS	France